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To Examiner: Stephen D. Rosasco	Total Pages Sent: 12
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Facsimile Number: (571) 273-8300	Transmission Date: March 8, 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICEApplicant: Schulze, *et al.*Docket No.: 115747-0003//
2002P50544US

Serial No.: 10/753,604

Art Unit: 1756

Date Filed: January 8, 2004

TITLE: Method For The Repair Of Defects In Photolithographic Masks For Patterning
Semiconductor Wafers**CERTIFICATION OF FACSIMILE TRANSMISSION**

I hereby certify that the following papers are being transmitted by facsimile to Mail Stop
Amendment at the U.S. Patent and Trademark Office at (571) 273-8300 on March 8, 2006:

- Certification of Facsimile Transmission (1 page)
- Amendment (11 pages)

Respectfully submitted,

Kristy Engeldahl
Legal Assistant**Confirmation Respectfully Requested**

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Filed: January 8, 2004 Examiner: Stephen D. Rosasco
For: Method For The Repair Of Defects In Photolithographic Masks For
Patterning Semiconductor Wafers

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

The following amendments and remarks are presented in response to the Examiner's Office Action mailed December 8, 2005. Please amend the above-referenced application as follows.